

Claims

[c1] What is claimed is:

1. A wafer holder for semiconductor manufacturing equipment, the wafer holder having a wafer-carrying surface and characterized in that the diameter a of the wafer holder wafer-carrying surface is not greater than the diameter b of the wafer holder surface on its side opposite the wafer-carrying surface.

[c2] 2. The wafer holder set forth in claim 1, wherein the diameter b is larger than the diameter a by 50 μm or more.

[c3] 3. The wafer holder set forth in claim 1, being a ceramic susceptor interiorly in or superficially on which a resistive heating element is formed.

[c4] 4. The wafer holder set forth in claim 2, being a ceramic susceptor interiorly in or superficially on which a resistive heating element is formed.

[c5] 5. Semiconductor manufacturing equipment wherein the wafer holder set forth in claim 1 is installed.

[c6] 6. Semiconductor manufacturing equipment wherein the wafer holder set forth in claim 2 is installed.

- [c7] 7. Semiconductor manufacturing equipment wherein the wafer holder set forth in claim 3 is installed.
- [c8] 8. Semiconductor manufacturing equipment wherein the wafer holder set forth in claim 4 is installed.